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8b Data Sheet

CONFIRMATION NO. 6404

SERIAL NUMBER 09/901,038	FILING DATE 07/10/2001 RULE	CLASS 438	GROUP ART UNIT 1765	ATTORNEY DOCKET NO. 50090-301
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APPLICANTS

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** CONTINUING DATA *YJ*** FOREIGN APPLICATIONS *YJ*

JAPAN 2000-403083 12/28/2000 *YJ*

IF REQUIRED, FOREIGN FILING LICENSE GRANTED

** 08/23/2001

Foreign Priority claimed	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY JAPAN	SHEETS DRAWING 3	TOTAL CLAIMS 18	INDEPENDENT CLAIMS 2
35 USC 119 (a-d) conditions met	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance <i>YJ</i>				

ADDRESS

McDermott, Will & Emery
 600 13th Street, N.W.
 Washington ,DC 20005-3096

TITLE

Plasma processing system in which wafer is retained by electrostatic chuck, plasma-processing method and method of manufacturing semiconductor device

*me
8/11/06*

FILING FEE RECEIVED 710	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:	<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit
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